

Contents

1. Introduction	1
1.1 Principle of the Scanning Electron Microscope	1
1.2 Electron-Specimen Interactions	3
1.3 Imaging Modes of Scanning Electron Microscopy	7
1.3.1 Secondary Electrons (SE)	7
1.3.2 Backscattered Electrons (BSE)	8
1.3.3 Specimen Current	8
1.3.4 Transmitted Electrons	9
1.3.5 Electron-Beam-Induced Current (EBIC)	9
1.3.6 Cathodoluminescence	9
1.3.7 Acoustic Thermal-Wave Microscopy	10
1.3.8 Environmental Electron Microscopy	10
1.3.9 Imaging with X-Rays	10
1.4 Analytical Modes	11
1.4.1 Crystal Structure and Orientation	11
1.4.2 Elemental Microanalysis	12
2. Electron Optics of a Scanning Electron Microscope	13
2.1 Electron Guns	13
2.1.1 Thermionic Electron Guns	13
2.1.2 Schottky-Emission Guns	17
2.1.3 Field-Emission Guns	18
2.1.4 Measurement of Gun Parameters	19
2.2 Electron Optics	21
2.2.1 Focal Length of an Electron Lens	21
2.2.2 Lens Aberrations	23
2.2.3 Special Designs of Objective Lenses	27
2.2.4 Geometric Optical Theory of Electron-Probe Formation	30
2.2.5 Wave-Optical Theory of Electron-Probe Formation	34
2.2.6 Stabilisation of the Electron-Probe Current	37
2.3 Electron Beam Deflection Modes	38
2.3.1 Electron Beam Deflection by Transverse Fields	38
2.3.2 Scanning, Magnification and Rocking	40

2.3.3	Electron Beam Blanking and Chopping	42
2.4	Focusing	46
2.4.1	Focusing and Correction of Astigmatism	46
2.4.2	Depth of Focus.....	49
2.4.3	Dynamic and Automatic Focusing	50
2.4.4	Resolution and Electron-Probe Size	52
3.	Electron Scattering and Diffusion	57
3.1	Elastic Scattering	57
3.1.1	Elastic Differential Cross-Section	57
3.1.2	Classical Mechanics of Electron-Nucleus Scattering ...	59
3.1.3	The Relativistic Schrödinger and Pauli-Dirac Equations	61
3.1.4	Quantum Mechanics of Scattering	63
3.1.5	Rutherford Scattering at a Screened Nucleus	66
3.1.6	Exact Mott Cross-Sections	69
3.2	Inelastic Scattering	73
3.2.1	Electron Excitation Processes and Energy Losses	73
3.2.2	Electron-Electron Collisions	76
3.2.3	Quantum Mechanics of Inner-Shell Ionization	78
3.2.4	Angular Distribution of Total Inelastic Scattering ...	81
3.3	Multiple Scattering Effects.....	82
3.3.1	Mean-Free-Path Length	82
3.3.2	Angular Distribution of Transmitted Electrons	84
3.3.3	Spatial Beam Broadening.....	87
3.3.4	Continuous-Slowing-Down Approximation	90
3.3.5	Modification of the Stopping Power at Low Electron Energies	93
3.3.6	Distribution of Energy Losses	94
3.4	Electron Diffusion	98
3.4.1	Transmission and Electron Range	98
3.4.2	Spatial and Depth Distribution of Energy Dissipation .	101
3.4.3	Diffusion Models	106
3.4.4	General Transport Equation	110
3.4.5	Special Solutions of the Transport Equation	112
3.4.6	Monte Carlo Simulations	114
3.5	Specimen Heating and Damage.....	117
3.5.1	Specimen Heating	117
3.5.2	Charging of Insulating Specimens	120
3.5.3	Radiation Damage of Organic and Inorganic Specimens	130
3.5.4	Contamination	132

4. Emission of Backscattered and Secondary Electrons	135
4.1 Backscattered Electrons	135
4.1.1 Measurement of the Backscattering Coefficient and the Secondary Electron Yield	135
4.1.2 Backscattering from Films and Particles	138
4.1.3 Backscattering from Solid Specimens	142
4.1.4 Angular Distribution of Backscattering	146
4.1.5 Energy Distribution of Backscattered Electrons and Low-loss Electrons	148
4.2 Secondary Electrons	152
4.2.1 Dependence of Secondary Electron Yield on Beam and Specimen Parameters	152
4.2.2 Physics of Secondary-Electron Emission	158
4.2.3 Contribution of Backscattered Electrons to the Secondary Electron Yield	162
4.2.4 Statistics of BSE and SE Emission	165
5. Electron Detectors and Spectrometers	171
5.1 Measurement of Small Currents	171
5.2 Scintillation Detectors and Multipliers	172
5.2.1 Scintillation Materials	172
5.2.2 Scintillator-Photomultiplier Combination	173
5.2.3 Electron Channel Multipliers	176
5.3 Semiconductor Detectors	177
5.3.1 Surface Barrier and p-n Junction Diodes	177
5.3.2 The Electronic Circuit of Semiconductor Detectors	181
5.4 Secondary and Backscattered Electron Detectors	183
5.4.1 Secondary Electron Detectors	183
5.4.2 Backscattered Electron Detectors	188
5.4.3 Multiple Detector Systems	191
5.5 Detector Noise	193
5.5.1 Noise of a Scintillator-Photomultiplier Combination	193
5.5.2 Noise of Semiconductor Detectors	196
5.6 Electron Spectrometers and Filters	197
5.6.1 Types of Electron Spectrometer	197
5.6.2 Secondary Electron Spectrometers	200
5.6.3 Backscattered and Auger Electron Spectrometers	203
6. Image Contrast and Signal Processing	207
6.1 Secondary Electron Imaging Mode	207
6.1.1 Types of Image Contrast	207
6.1.2 Topographic Contrast in the SE Mode	208
6.1.3 Material Contrast in the SE Mode	214
6.1.4 Detector Strategies for the SE Mode	217
6.2 Backscattered Electron Imaging Modes	222

6.2.1	Topographic and Material Contrast in the BSE Mode .	222
6.2.2	Channelling or Crystal Orientation Contrast	225
6.2.3	Contrast of BSE Using Multiple Detector Systems	227
6.2.4	Quantitative Information from the BSE Signal	228
6.2.5	Energy-Filtering of Backscattered Electrons.....	231
6.2.6	The Specimen-Current Mode	233
6.3	Resolution and Contrast in the SE and BSE Modes	234
6.3.1	Secondary-Electron Mode	234
6.3.2	Backscattered Electron Mode	235
6.4	Image Recording and Processing	237
6.4.1	Observation and Recording on Cathode-Ray Tubes ...	237
6.4.2	Analogue Signal-Processing Methods.....	240
6.4.3	Digital Image Acquisition	244
6.4.4	Digital Image Processing	245
6.4.5	Stereogrammetry	250
7.	Electron-Beam-Induced Current and Cathodoluminescence	253
7.1	Electron-Beam-Induced Current (EBIC) Mode	253
7.1.1	EBIC Modes and Specimen Geometry	253
7.1.2	Charge Carrier Generation, Diffusion and Collection .	256
7.1.3	Quantitative Measurement of Semiconductor Parameters	261
7.1.4	EBIC Imaging of Depletion Layers.....	264
7.1.5	EBIC Imaging and Defect Analysis	266
7.1.6	Scanning Deep-Level Transient Spectroscopy (SDLTS)	268
7.1.7	Radiation Damage Effects in Semiconductor Devices ..	269
7.1.8	EBIC and EBIV Without Any Depletion Layer and in Superconductors	270
7.2	Cathodoluminescence	273
7.2.1	Basic Mechanisms of Cathodoluminescence	273
7.2.2	Detection and Spectrometry of Light Quanta	276
7.2.3	Quantitative Cathodoluminescence of Semiconductors .	280
7.2.4	Cathodoluminescence Imaging Mode	284
7.2.5	Cathodoluminescence of Organic Specimens	287
8.	Special Techniques in SEM	289
8.1	Imaging and Measurement of Magnetic Fields	289
8.1.1	Type-1 Magnetic Contrast	290
8.1.2	Type-2 Magnetic Contrast	293
8.1.3	Deflection of Primary Electrons by Magnetic Fields ...	296
8.1.4	Imaging of Surface Magnetization by Polarized Electrons	298
8.2	Voltage Contrast	299
8.2.1	Qualitative Voltage Contrast	299

8.2.2	Voltage Contrast on Ferroelectrics and Piezoelectrics ..	301
8.2.3	Quantitative Measurement of Surface Potential	303
8.2.4	Stroboscopic Measurement of Voltages	306
8.2.5	Capacitive-Coupling Voltage Contrast	307
8.2.6	Capacitively Induced Charging in an External Electrode	308
8.3	Low-Energy Spectroscopies	308
8.3.1	Threshold Spectroscopies	308
8.3.2	Electron Trap Spectroscopy and Microscopy	309
8.4	Transmitted Electron Mode	312
8.5	Scanning Electron Mirror Microscopy	314
8.6	Environmental Scanning Electron Microscopy (ESEM)	316
8.7	Scanning Electron Acoustic Microscopy	321
8.8	Electron-Beam Lithography and Metrology	324
8.9	Combination of SEM and STM	328
9.	Crystal Structure Analysis by Diffraction	329
9.1	Theory of Electron Diffraction	329
9.1.1	Kinematical Theory and Bragg Condition	329
9.1.2	Kossel Cones and Kossel Maps	334
9.1.3	Dynamical Theory of Electron Diffraction and Bloch Waves	338
9.1.4	Orientation Anisotropy of Electron Backscattering ...	349
9.1.5	Angular Anisotropy of Electron Backscattering	354
9.1.6	Transmission and Reflection Electron Diffraction Patterns	356
9.2	Electron Channelling Patterns (ECP)	359
9.2.1	Electron-Optical Parameters for the Recording of ECP	359
9.2.2	The Standard and Tilt Method of Generating ECP ...	361
9.2.3	Small-Area Methods for ECP	363
9.2.4	Recording of Electron Channelling Patterns	365
9.2.5	Information in Electron Channelling Patterns	366
9.3	Electron Backscattering Patterns (EBSP)	368
9.3.1	Recording of EBSP	368
9.3.2	Advantages of EBSP over ECP	370
9.3.3	The Reciprocity Theorem Between ECP and EBSP ...	371
9.3.4	Determination of Crystal Structure and Orientation ..	373
9.4	X-Ray Kossel Patterns	374
9.4.1	Generation and Recording of X-Ray Kossel Patterns ..	374
9.4.2	Information from X-Ray Kossel Patterns	375

10. Elemental Analysis and Imaging with X-Rays	379
10.1 X-Ray and Auger Electron Emission	380
10.1.1 X-Ray Spectra	380
10.1.2 The X-Ray Continuum	381
10.1.3 The Characteristic X-Ray Spectrum	385
10.1.4 Absorption of X-Rays	390
10.1.5 Auger Electron Emission	393
10.2 X-Ray Spectrometers	396
10.2.1 Wavelength-Dispersive X-Ray Spectrometers	396
10.2.2 Energy-Dispersive X-Ray Spectrometers	399
10.2.3 Electronic Circuit of an Energy-Dispersive Spectrometer	403
10.2.4 Comparison of Wavelength- and Energy-Dispersive Spectrometers	406
10.3 Correction Methods for X-Ray Microanalysis	407
10.3.1 Problems of Quantitative Analysis	407
10.3.2 X-Ray Excitation and Atomic Number Correction	410
10.3.3 Depth Distribution of X-Ray Production and the Absorption Correction	416
10.3.4 Fluorescence Correction	420
10.3.5 Refined Methods and Standardless X-Ray Microanalysis	425
10.3.6 X-Ray Microanalysis of Nonconducting Specimens	426
10.4 X-Ray Microanalysis for Special Geometries	427
10.4.1 Tilted Specimens	427
10.4.2 Perpendicular Interfaces and Spatial Distribution of X-Ray Emission	429
10.4.3 Thin Films on Substrates	430
10.4.4 Free-Supporting Films and Particles	432
10.4.5 X-Ray Microanalysis of Biological Specimens	433
10.5 Data Processing and Sensitivity in X-Ray and Auger Electron Analysis	436
10.5.1 Background and Peak-Overlap Correction	436
10.5.2 Counting Statistics and Sensitivity	436
10.5.3 X-Ray Fluorescence Spectroscopy in SEM	438
10.5.4 Auger Electron and X-Ray Photoelectron Spectroscopy	439
10.6 Imaging Methods with X-Rays	441
10.6.1 X-Ray Mapping and Linescans	441
10.6.2 Total Rate Imaging with X-Rays (TRIX)	444
10.6.3 X-Ray Projection Microscopy and Tomography	444
References	449
Index	515